Eda Goldenberg

List of Publications by Year
in descending order

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30	684	471477 17	552766 26
papers	citations	h-index	g-index

30	30	30	904
all docs	docs citations	times ranked	citing authors

#	Article	IF	Citations
1	Hollow cathode plasma-assisted atomic layer deposition of crystalline AlN, GaN and Al_xGa_{1â^'x}N thin films at low temperatures. Journal of Materials Chemistry C, 2014, 2, 2123-2136.	5.5	133
2	Effects of deposition time and temperature on the optical properties of air-annealed chemical bath deposited CdS films. Thin Solid Films, 2006, 515, 1688-1693.	1.8	57
3	Modeling the optical properties of tin oxide thin films. Thin Solid Films, 2009, 517, 5146-5150.	1.8	45
4	Chemical and thermal stability of the characteristics of filtered vacuum arc deposited ZnO, SnO₂and zinc stannate thin films. Journal Physics D: Applied Physics, 2007, 40, 5220-5226.	2.8	40
5	Lowâ€Temperature Deposition of Hexagonal Boron Nitride via Sequential Injection of Triethylboron and N₂/H₂ Plasma. Journal of the American Ceramic Society, 2014, 97, 4052-4059.	3.8	33
6	The effect of annealing on filtered vacuum arc deposited ZnO thin films. Surface and Coatings Technology, 2007, 201, 7266-7272.	4.8	31
7	Properties of SnO2 films fabricated using a rectangular filtered vacuum arc plasma source. Thin Solid Films, 2008, 516, 5079-5086.	1.8	31
8	Influence of annealing on the physical properties of filtered vacuum arc deposited tin oxide thin films. Journal of Non-Crystalline Solids, 2007, 353, 2595-2602.	3.1	28
9	Fabrication of flexible polymerâ€“GaN coreâ€“shell nanofibers by the combination of electrospinning and hollow cathode plasma-assisted atomic layer deposition. Journal of Materials Chemistry C, 2015, 3, 5199-5206.	5.5	26
10	Air annealing effects on the optical properties of ZnOâ€“SnO2thin films deposited by a filtered vacuum arc deposition system. Semiconductor Science and Technology, 2006, 21, 364-369.	2.0	25
11	Filtered vacuum arc deposition of transparent conducting Al-doped ZnO films. Thin Solid Films, 2006, 515, 885-890.	1.8	24
12	Effect of deposition conditions on the characteristics of ZnOâ€“SnO2 thin films deposited by filtered vacuum arc. Thin Solid Films, 2006, 515, 880-884.	1.8	21
13	Characteristics of filtered vacuum arc deposited ZnOâ€“SnO2 thin films on room temperature substrates. Optics Communications, 2007, 280, 114-119.	2.1	20
14	Structural, optical and electrical characteristics BaSrTiOx thin films: Effect of deposition pressure and annealing. Journal of Non-Crystalline Solids, 2017, 475, 76-84.	3.1	19
15	Optical properties of transparent ZnOâ€“SnO2thin films deposited by filtered vacuum arc. Journal Physics D: Applied Physics, 2006, 39, 1878-1884.	2.8	18
16	Low-temperature grown wurtzite In_xGa_{1â^'x}N thin films via hollow cathode plasma-assisted atomic layer deposition. Journal of Materials Chemistry C, 2015, 3, 9620-9630.	5.5	18
17	The effect of substrate temperature on filtered vacuum arc deposited zinc oxide and tin oxide thin films. Journal of Crystal Growth, 2007, 299, 259-267.	1.5	17
18	Optical characterization of filtered vacuum arc deposited zinc oxide thin films. Semiconductor Science and Technology, 2006, 21, 1303-1310.	2.0	16

#	Article	IF	Citations
19	Effect of O2/Ar flow ratio and post-deposition annealing on the structural, optical and electrical characteristics of SrTiO3 thin films deposited by RF sputtering at room temperature. Thin Solid Films, 2015, 590, 193-199.	1.8	14
20	WS<mml:math xmlns:mml="http://www.w3.org/1998/Math/MathML" altimg="si2.svg"><mml:msub><mml:mrow /><mml:mn>2</mml:mn></mml:msub></mml:math> thin film based quartz crystal microbalance gas sensor for dimethyl methylphosphonate detection at room temperature. Thin Solid Films, 2022, 745, 139097.	1.8	13
21	Optical characteristics of nanocrystalline AlxGa1â^'xN thin films deposited by hollow cathode plasma-assisted atomic layer deposition. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2014, 32, .	2.1	12
22	Lowâ€temperature hollow cathode plasmaâ€assisted atomic layer deposition of crystalline IIIâ€nitride thin films and nanostructures. Physica Status Solidi C: Current Topics in Solid State Physics, 2015, 12, 394-398.	0.8	11
23	Postdeposition annealing on RF-sputtered SrTiO3 thin films. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2017, 35, .	2.1	11
24	Structural and optical characteristics of filtered vacuum arc deposited N:TiOx thin films. Thin Solid Films, 2013, 537, 28-35.	1.8	7
25	The dependence of filtered vacuum arc deposited ZnOâ€“SnO2thin films characteristics on substrate temperature. Journal Physics D: Applied Physics, 2006, 39, 5245-5251.	2.8	6
26	The effect of post-deposition annealing on the optical properties of filtered vacuum arc deposited ZnOâ€“SnO2. Journal of Physics Condensed Matter, 2007, 19, 256206.	1.8	4
27	Hollow-cathode plasma-assisted atomic layer deposition: A novel route for low-temperature synthesis of crystalline III-nitride thin films and nanostructures. , 2015, , .		2
28	Phase determination of filtered vacuum arc deposited TiO2 thin films by optical modeling. Thin Solid Films, 2009, 518, 1060-1066.	1.8	1
29	Zno nanostructures via hydrothermal synthesis on atomic layer deposited seed-layers. , 2015, , .		1
30	Electroâ€optical performances of nanostructured SrTiO x films: The effect of plasma power, Ar/O 2 ratio and annealing. International Journal of Applied Ceramic Technology, 2021, 18, 631-642.	2.1	0